

Andre Anders

List of Publications by Year in Descending Order

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The third column is the impact factor (IF) of the journal, and the fourth column is the number of citations of the article.

377
papers

13,674
citations

59
h-index

100
g-index

426
ext. papers

15,096
ext. citations

2.7
avg, IF

7.07
L-index

#	Paper	IF	Citations
377	On the population density of the argon excited levels in a high power impulse magnetron sputtering discharge. <i>Physics of Plasmas</i> , 2022 , 29, 023506	2.1	
376	High-quality transparent conductive indium oxide film deposition by reactive pulsed magnetron sputtering: Determining the limits of substrate heating. <i>Applied Surface Science</i> , 2022 , 585, 152604	6.7	2
375	Dynamics and 2D temperature distribution of plasma obtained by femtosecond laser-induced breakdown. <i>Journal Physics D: Applied Physics</i> , 2022 , 55, 125204	3	2
374	Properties of gallium oxide thin films grown by ion beam sputter deposition at room temperature. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2022 , 40, 033409	2.9	0
373	High-resolution observation of cathodic arc spots in a magnetically steered arc plasma source in low pressure argon, nitrogen, and oxygen atmospheres. <i>Journal of Applied Physics</i> , 2021 , 130, 183304	2.5	0
372	On the electron energy distribution function in the high power impulse magnetron sputtering discharge. <i>Plasma Sources Science and Technology</i> , 2021 , 30, 045011	3.5	5
371	Role of Reaction Intermediate Diffusion on the Performance of Platinum Electrodes in Solid Acid Fuel Cells. <i>Catalysts</i> , 2021 , 11, 1065	4	2
370	Unravelling the ion-energy-dependent structure evolution and its implications for the elastic properties of (V,Al)N thin films. <i>Acta Materialia</i> , 2021 , 214, 117003	8.4	4
369	Cathode spot behavior in nitrogen and oxygen gaseous atmospheres and concomitant cathode surface modifications. <i>Surface and Coatings Technology</i> , 2021 , 421, 127441	4.4	1
368	High-resolution observation of cathode spots in a magnetically steered vacuum arc plasma source. <i>Plasma Sources Science and Technology</i> , 2021 , 30, 095005	3.5	1
367	Properties of secondary ions in ion beam sputtering of Ga ₂ O ₃ . <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2021 , 39, 053409	2.9	2
366	On how to measure the probabilities of target atom ionization and target ion back-attraction in high-power impulse magnetron sputtering. <i>Journal of Applied Physics</i> , 2021 , 129, 033303	2.5	5
365	Electron transport in high power impulse magnetron sputtering at low and high working gas pressure. <i>Journal of Applied Physics</i> , 2021 , 130, 243301	2.5	1
364	Insights into surface modification and erosion of multi-element arc cathodes using a novel multilayer cathode design. <i>Journal of Applied Physics</i> , 2020 , 127, 113301	2.5	6
363	Optimizing the deposition rate and ionized flux fraction by tuning the pulse length in high power impulse magnetron sputtering. <i>Plasma Sources Science and Technology</i> , 2020 , 29, 05LT01	3.5	22
362	Properties of secondary particles for ion beam sputtering of silicon using low-energy oxygen ions. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2020 , 38, 033011	2.9	6
361	Erosion and cathodic arc plasma of Nb/Al cathodes: composite versus intermetallic. <i>Plasma Sources Science and Technology</i> , 2020 , 29, 025022	3.5	6

360	Vanadium oxide coatings to self-regulate current sharing in high-temperature superconducting cables and magnets. <i>Journal of Applied Physics</i> , 2020 , 128, 055105	2.5	4
359	Physics of high power impulse magnetron sputtering discharges 2020 , 265-332		4
358	Ion beam sputtering of silicon: Energy distributions of sputtered and scattered ions. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2019 , 37, 051507	2.9	10
357	Micro-propulsion based on vacuum arcs. <i>Journal of Applied Physics</i> , 2019 , 125, 220902	2.5	26
356	Influence of Ar gas pressure on ion energy and charge state distributions in pulsed cathodic arc plasmas from NbAl cathodes studied with high time resolution. <i>Journal Physics D: Applied Physics</i> , 2019 , 52, 055201	3	3
355	Plasma studies of a linear magnetron operating in the range from DC to HiPIMS. <i>Journal of Applied Physics</i> , 2018 , 123, 043302	2.5	17
354	Reduced atomic shadowing in HiPIMS: Role of the thermalized metal ions. <i>Applied Surface Science</i> , 2018 , 433, 934-944	6.7	21
353	Time-resolved ion energy and charge state distributions in pulsed cathodic arc plasmas of NbAl cathodes in high vacuum. <i>Plasma Sources Science and Technology</i> , 2018 , 27, 055007	3.5	6
352	Structural and Optical Studies of InGaN/GaN Superlattices Implanted with Eu Ions. <i>MRS Advances</i> , 2017 , 2, 179-187	0.7	
351	Plasma potential of a moving ionization zone in DC magnetron sputtering. <i>Journal of Applied Physics</i> , 2017 , 121, 063302	2.5	50
350	Sputtering of pure boron using a magnetron without a radio-frequency supply. <i>Review of Scientific Instruments</i> , 2017 , 88, 043506	1.7	6
349	Tutorial: Reactive high power impulse magnetron sputtering (R-HiPIMS). <i>Journal of Applied Physics</i> , 2017 , 121, 171101	2.5	199
348	Direct observation of spoke evolution in magnetron sputtering. <i>Applied Physics Letters</i> , 2017 , 111, 064103	3.4	19
347	Phase tailoring of tantalum thin films deposited in deep oscillation magnetron sputtering mode. <i>Surface and Coatings Technology</i> , 2017 , 314, 97-104	4.4	21
346	Micropropulsion Based on Vacuum Arc Physics and Technology: A Review 2016 ,		1
345	Influence of ionisation zone motion in high power impulse magnetron sputtering on angular ion flux and NbOx film growth. <i>Plasma Sources Science and Technology</i> , 2016 , 25, 015022	3.5	22
344	Tunable Bragg filters with a phase transition material defect layer. <i>Optics Express</i> , 2016 , 24, 20365-72	3.3	11
343	Evidence for breathing modes in direct current, pulsed, and high power impulse magnetron sputtering plasmas. <i>Applied Physics Letters</i> , 2016 , 108, 034101	3.4	19

342	Element- and charge-state-resolved ion energies in the cathodic arc plasma from composite AlCr cathodes in argon, nitrogen and oxygen atmospheres. <i>Surface and Coatings Technology</i> , 2015 , 272, 309-321	4.4	11
341	Adding high time resolution to charge-state-specific ion energy measurements for pulsed copper vacuum arc plasmas. <i>Plasma Sources Science and Technology</i> , 2015 , 24, 045010	3.5	12
340	. <i>IEEE Transactions on Plasma Science</i> , 2015 , 43, 2310-2317	1.3	11
339	Ion energies in high power impulse magnetron sputtering with and without localized ionization zones. <i>Applied Physics Letters</i> , 2015 , 106, 124102	3.4	21
338	Temporal evolution of ion energy distribution functions and ion charge states of Cr and Cr-Al pulsed arc plasmas. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2015 , 33, 061301	2.9	6
337	Room Temperature Oxide Deposition Approach to Fully Transparent, All-Oxide Thin-Film Transistors. <i>Advanced Materials</i> , 2015 , 27, 6090-5	24	49
336	2-D mathematical modeling for a large electrochromic window Part I. <i>Solar Energy Materials and Solar Cells</i> , 2014 , 120, 1-8	6.4	17
335	Smoothing of Discharge Inhomogeneities at High Currents in Gasless High Power Impulse Magnetron Sputtering. <i>IEEE Transactions on Plasma Science</i> , 2014 , 42, 2856-2857	1.3	10
334	Drifting Ionization Zone in DC Magnetron Sputtering Discharges at Very Low Currents. <i>IEEE Transactions on Plasma Science</i> , 2014 , 42, 2578-2579	1.3	18
333	Unusual Cathode Erosion Patterns Observed for Steered Arc Sources. <i>IEEE Transactions on Plasma Science</i> , 2014 , 42, 2602-2603	1.3	3
332	Asymmetric particle fluxes from drifting ionization zones in sputtering magnetrons. <i>Plasma Sources Science and Technology</i> , 2014 , 23, 025007	3.5	40
331	On the road to self-sputtering in high power impulse magnetron sputtering: particle balance and discharge characteristics. <i>Plasma Sources Science and Technology</i> , 2014 , 23, 025017	3.5	38
330	A review comparing cathodic arcs and high power impulse magnetron sputtering (HiPIMS). <i>Surface and Coatings Technology</i> , 2014 , 257, 308-325	4.4	156
329	Observation of multiple charge states and high ion energies in high-power impulse magnetron sputtering (HiPIMS) and burst HiPIMS using a LaB ₆ target. <i>Plasma Sources Science and Technology</i> , 2014 , 23, 035001	3.5	16
328	Localized heating of electrons in ionization zones: Going beyond the Penning-Thornton paradigm in magnetron sputtering. <i>Applied Physics Letters</i> , 2014 , 105, 244104	3.4	39
327	Propagation direction reversal of ionization zones in the transition between high and low current magnetron sputtering. <i>Applied Physics Letters</i> , 2014 , 105, 254101	3.4	29
326	Controlling ion fluxes during reactive sputter-deposition of SnO ₂ :F. <i>Journal of Applied Physics</i> , 2014 , 116, 033301	2.5	18
325	Fermi level stabilization and band edge energies in Cd _x Zn _{1-x} O alloys. <i>Journal of Applied Physics</i> , 2014 , 115, 233708	2.5	31

324	Ion energies in vacuum arcs: A critical review of data and theories leading to traveling potential humps 2014 ,		3
323	Spectroscopic imaging of self-organization in high power impulse magnetron sputtering plasmas. <i>Applied Physics Letters</i> , 2013 , 103, 054104	3-4	44
322	On sheath energization and Ohmic heating in sputtering magnetrons. <i>Plasma Sources Science and Technology</i> , 2013 , 22, 045005	3-5	51
321	Size and composition-controlled fabrication of thermochromic metal oxide nanocrystals. <i>Journal Physics D: Applied Physics</i> , 2013 , 46, 362001	3	16
320	Drifting potential humps in ionization zones: The propeller blades of high power impulse magnetron sputtering. <i>Applied Physics Letters</i> , 2013 , 103, 144103	3-4	58
319	Transparent and conductive indium doped cadmium oxide thin films prepared by pulsed filtered cathodic arc deposition. <i>Applied Surface Science</i> , 2013 , 265, 738-744	6-7	49
318	Structural, optical, and electrical properties of indium-doped cadmium oxide films prepared by pulsed filtered cathodic arc deposition. <i>Journal of Materials Science</i> , 2013 , 48, 3789-3797	4-3	26
317	Dopant-induced band filling and bandgap renormalization in CdO : In films. <i>Journal Physics D: Applied Physics</i> , 2013 , 46, 195102	3	34
316	Estimating electron drift velocities in magnetron discharges. <i>Vacuum</i> , 2013 , 89, 53-56	3-7	13
315	Crystal structure and properties of Cd _x Zn _{1-x} O alloys across the full composition range. <i>Applied Physics Letters</i> , 2013 , 102, 232103	3-4	52
314	Modeling of optical and energy performance of tungsten-oxide-based electrochromic windows including their intermediate states. <i>Solar Energy Materials and Solar Cells</i> , 2013 , 108, 129-135	6-4	28
313	Ion Charge State Distributions of Al and Cr in Cathodic Arc Plasmas From Composite Cathodes in Vacuum, Argon, Nitrogen, and Oxygen. <i>IEEE Transactions on Plasma Science</i> , 2013 , 41, 1929-1937	1-3	13
312	Plasma flares in high power impulse magnetron sputtering. <i>Applied Physics Letters</i> , 2012 , 101, 224102	3-4	40
311	Thermal decomposition and fractal properties of sputter-deposited platinum oxide thin films. <i>Journal of Materials Research</i> , 2012 , 27, 829-836	2-5	9
310	The recycling trap: a generalized explanation of discharge runaway in high-power impulse magnetron sputtering. <i>Journal Physics D: Applied Physics</i> , 2012 , 45, 012003	3	68
309	Determining the nonparabolicity factor of the CdO conduction band using indium doping and the Drude theory. <i>Journal Physics D: Applied Physics</i> , 2012 , 45, 425302	3	33
308	The evolution of ion charge states in cathodic vacuum arc plasmas: a review. <i>Plasma Sources Science and Technology</i> , 2012 , 21, 035014	3-5	47
307	Phase transitions in vacuum arcs in the context of liquid metal arc sources 2012 ,		3

306	Self-organization and self-limitation in high power impulse magnetron sputtering. <i>Applied Physics Letters</i> , 2012 , 100, 224104	3.4	56
305	Plasma potential mapping of high power impulse magnetron sputtering discharges. <i>Journal of Applied Physics</i> , 2012 , 111, 083302	2.5	65
304	Modelling of target effects in reactive HIPIMS. <i>IOP Conference Series: Materials Science and Engineering</i> , 2012 , 39, 012008	0.4	5
303	Efficient, Low Cost Synthesis of Sodium Platinum Bronze Na ₃ Pt ₃ O ₄ . <i>Chemistry of Materials</i> , 2012 , 24, 2429-2432	9.6	5
302	Gas rarefaction and the time evolution of long high-power impulse magnetron sputtering pulses. <i>Plasma Sources Science and Technology</i> , 2012 , 21, 045004	3.5	63
301	Evaluation of species-specific score cutoff values of routinely isolated clinically relevant bacteria using a direct smear preparation for matrix-assisted laser desorption/ionization time-of-flight mass spectrometry-based bacterial identification. <i>European Journal of Clinical Microbiology and Infectious Diseases</i> , 2012 , 31, 1189-1196	5.3	30
300	Drifting localization of ionization runaway: Unraveling the nature of anomalous transport in high power impulse magnetron sputtering. <i>Journal of Applied Physics</i> , 2012 , 111, 053304	2.5	115
299	Charge state distributions of Al and Cr cathodic arc plasmas 2012 ,		1
298	Improved structural and electrical properties of thin ZnO:Al films by dc filtered cathodic arc deposition. <i>Journal of Materials Research</i> , 2012 , 27, 857-862	2.5	3
297	Plasma and Ion-Beam Assisted Materials Processing. <i>Journal of Materials Research</i> , 2012 , 27, 741-742	2.5	
296	A synchronized emissive probe for time-resolved plasma potential measurements of pulsed discharges. <i>Review of Scientific Instruments</i> , 2011 , 82, 093505	1.7	10
295	Dynamically modulating the surface plasmon resonance of doped semiconductor nanocrystals. <i>Nano Letters</i> , 2011 , 11, 4415-20	11.5	423
294	Measurements of the Ion Species of Cathodic Arc Plasma in an Axial Magnetic Field. <i>IEEE Transactions on Plasma Science</i> , 2011 , 39, 1272-1276	1.3	7
293	. <i>IEEE Transactions on Plasma Science</i> , 2011 , 39, 1386-1393	1.3	7
292	Chemistry, phase formation, and catalytic activity of thin palladium-containing oxide films synthesized by plasma-assisted physical vapor deposition. <i>Surface and Coatings Technology</i> , 2011 , 205, S171-S177	4.4	17
291	Discharge physics of high power impulse magnetron sputtering. <i>Surface and Coatings Technology</i> , 2011 , 205, S1-S9	4.4	194
290	A Plasma Lens for Magnetron Sputtering. <i>IEEE Transactions on Plasma Science</i> , 2011 , 39, 2528-2529	1.3	18
289	Identification of Ternary Phases in TiBC/a-C Nanocomposite Thin Films: Influence on the Electrical and Optical Properties. <i>Plasma Processes and Polymers</i> , 2011 , 8, 579-588	3.4	9

288	Optical properties of ferromagnetic ytterbium-doped III-nitride epilayers. <i>Physica Status Solidi C: Current Topics in Solid State Physics</i> , 2011 , 8, 2185-2187		4
287	. <i>IEEE Transactions on Applied Superconductivity</i> , 2011 , 21, 2550-2553	1.8	6
286	Achieving high mobility ZnO : Al at very high growth rates by dc filtered cathodic arc deposition. <i>Journal Physics D: Applied Physics</i> , 2011 , 44, 232003	3	32
285	Preparation of high transmittance ZnO:Al film by pulsed filtered cathodic arc technology and rapid thermal annealing. <i>Applied Surface Science</i> , 2011 , 257, 7019-7022	6.7	8
284	Hollow Plasma in a Solenoid. <i>IEEE Transactions on Plasma Science</i> , 2011 , 39, 2888-2889	1.3	1
283	High Rate Deposition of High Quality ZnO:Al by Filtered Cathodic Arc. <i>Materials Research Society Symposia Proceedings</i> , 2011 , 1315, 1		1
282	Epitaxy of Ultrathin NiSi ₂ Films with Predetermined Thickness. <i>Electrochemical and Solid-State Letters</i> , 2011 , 14, H268		21
281	A self-sputtering ion source: a new approach to quiescent metal ion beams. <i>Review of Scientific Instruments</i> , 2010 , 81, 02B306	1.7	10
280	Resonant inelastic scattering spectra of free molecules with vibrational resolution. <i>Physical Review Letters</i> , 2010 , 104, 193002	7.4	114
279	Beneficial silver: antibacterial nanocomposite Ag-DLC coating to reduce osteolysis of orthopaedic implants. <i>Journal of Physics: Conference Series</i> , 2010 , 252, 012005	0.3	6
278	Ion acceleration and cooling in gasless self-sputtering. <i>Applied Physics Letters</i> , 2010 , 97, 221501	3.4	21
277	On the deactivation of the dopant and electronic structure in reactively sputtered transparent Al-doped ZnO thin films. <i>Journal Physics D: Applied Physics</i> , 2010 , 43, 132003	3	25
276	Compression and strong rarefaction in high power impulse magnetron sputtering discharges. <i>Journal of Applied Physics</i> , 2010 , 108, 123306	2.5	62
275	Origin of the Delayed Current Onset in High-Power Impulse Magnetron Sputtering. <i>IEEE Transactions on Plasma Science</i> , 2010 , 38, 3028-3034	1.3	53
274	Deposition rates of high power impulse magnetron sputtering: Physics and economics. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2010 , 28, 783-790	2.9	134
273	Distance-dependent plasma composition and ion energy in high power impulse magnetron sputtering. <i>Journal Physics D: Applied Physics</i> , 2010 , 43, 275204	3	18
272	Supersonic metal plasma impact on a surface: an optical investigation of the pre-surface region. <i>Journal Physics D: Applied Physics</i> , 2010 , 43, 135201	3	5
271	Antibacterial efficacy of advanced silver-amorphous carbon coatings deposited using the pulsed dual cathodic arc technique. <i>Journal of Physics: Conference Series</i> , 2010 , 252, 012012	0.3	16

270	Energetic deposition of metal ions: observation of self-sputtering and limited sticking for off-normal angles of incidence. <i>Journal Physics D: Applied Physics</i> , 2010 , 43, 065206	3	13
269	Unfiltered and Filtered Cathodic Arc Deposition 2010 , 466-531		10
268	High quality ZnO:Al transparent conducting oxide films synthesized by pulsed filtered cathodic arc deposition. <i>Thin Solid Films</i> , 2010 , 518, 3313-3319	2.2	46
267	A structure zone diagram including plasma-based deposition and ion etching. <i>Thin Solid Films</i> , 2010 , 518, 4087-4090	2.2	480
266	High power impulse magnetron sputtering and related discharges: Scalable plasma sources for plasma-based ion implantation and deposition. <i>Surface and Coatings Technology</i> , 2010 , 204, 2864-2868	4.4	45
265	Optical and magnetic properties of GaN epilayers implanted with ytterbium. <i>Journal of Rare Earths</i> , 2010 , 28, 931-935	3.7	10
264	Broad, intense, quiescent beam of singly charged metal ions obtained by extraction from self-sputtering plasma far above the runaway threshold. <i>Journal of Applied Physics</i> , 2009 , 106, 023306	2.5	10
263	Physical limits for high ion charge states in pulsed discharges in vacuum. <i>Journal of Applied Physics</i> , 2009 , 105, 043303	2.5	13
262	A discussion on the absence of plasma in spark plasma sintering. <i>Scripta Materialia</i> , 2009 , 60, 835-838	5.6	179
261	Electronic structure and conductivity of nanocomposite metal (Au, Ag, Cu, Mo)-containing amorphous carbon films. <i>Solid State Sciences</i> , 2009 , 11, 1742-1746	3.4	30
260	Impact of Annealing on the Conductivity of Amorphous Carbon Films Incorporating Copper and Gold Nanoparticles Deposited by Pulsed Dual Cathodic Arc. <i>Plasma Processes and Polymers</i> , 2009 , 6, S438-S443 ⁶	2.4	6
259	A space-charge-neutralizing plasma for beam drift compression. <i>Nuclear Instruments and Methods in Physics Research, Section A: Accelerators, Spectrometers, Detectors and Associated Equipment</i> , 2009 , 606, 22-30	1.2	20
258	Progress in beam focusing and compression for warm-dense matter experiments. <i>Nuclear Instruments and Methods in Physics Research, Section A: Accelerators, Spectrometers, Detectors and Associated Equipment</i> , 2009 , 606, 75-82	1.2	43
257	Surface transformation of graphite or diamond following Highly Charged Ion irradiation. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2009 , 267, 678-682	1.2	2
256	Electronic structure of water molecules confined in a micelle lattice. <i>Journal of Physical Chemistry B</i> , 2009 , 113, 8201-5	3.4	18
255	Local electronic structure of functional groups in glycine as anion, zwitterion, and cation in aqueous solution. <i>Journal of Physical Chemistry B</i> , 2009 , 113, 16002-6	3.4	35
254	Spectra and energy levels of Yb ³⁺ in AlN. <i>Journal of Applied Physics</i> , 2009 , 106, 013106	2.5	23
253	Evolution of the plasma composition of a high power impulse magnetron sputtering system studied with a time-of-flight spectrometer. <i>Journal of Applied Physics</i> , 2009 , 105, 093304	2.5	35

252	Self-sputtering far above the runaway threshold: an extraordinary metal-ion generator. <i>Physical Review Letters</i> , 2009 , 102, 045003	7.4	63
251	Plasma Anti-assistance and Self-assistance to high power impulse magnetron sputtering. <i>Journal of Applied Physics</i> , 2009 , 105, 073301	2.5	36
250	Simulations and experiments of intense ion beam current density compression in space and time. <i>Physics of Plasmas</i> , 2009 , 16, 056701	2.1	14
249	Deep oxidation of methane on particles derived from YSZ-supported PdPt-(O) coatings synthesized by Pulsed Filtered Cathodic Arc. <i>Catalysis Communications</i> , 2009 , 10, 1410-1413	3.2	9
248	Reactive Deposition. <i>Springer Series on Atomic, Optical, and Plasma Physics</i> , 2008 , 409-428	0.4	1
247	The absence of plasma in spark plasma sintering. <i>Journal of Applied Physics</i> , 2008 , 104, 033305	2.5	123
246	Film Deposition by Energetic Condensation. <i>Springer Series on Atomic, Optical, and Plasma Physics</i> , 2008 , 363-407	0.4	3
245	The Physics of Cathode Processes. <i>Springer Series on Atomic, Optical, and Plasma Physics</i> , 2008 , 75-174	0.4	6
244	Self-sputtering runaway in high power impulse magnetron sputtering: The role of secondary electrons and multiply charged metal ions. <i>Applied Physics Letters</i> , 2008 , 92, 201501	3.4	74
243	Gasless sputtering: Opportunities for ultraclean metallization, coatings in space, and propulsion. <i>Applied Physics Letters</i> , 2008 , 92, 221503	3.4	65
242	The electronic structure of tungsten oxide thin films prepared by pulsed cathodic arc deposition and plasma-assisted pulsed magnetron sputtering. <i>Journal of Physics Condensed Matter</i> , 2008 , 20, 175216	1.8	5
241	Cathodic Arcs. <i>Springer Series on Atomic, Optical, and Plasma Physics</i> , 2008 ,	0.4	361
240	Spatial distribution of average charge state and deposition rate in high power impulse magnetron sputtering of copper. <i>Journal Physics D: Applied Physics</i> , 2008 , 41, 135210	3	36
239	A Theoretical Analysis of Vacuum Arc Thruster and Vacuum Arc Ion Thruster Performance. <i>IEEE Transactions on Plasma Science</i> , 2008 , 36, 2167-2179	1.3	56
238	Electrical properties of a-C: Mo films produced by dual-cathode filtered cathodic arc plasma deposition. <i>Diamond and Related Materials</i> , 2008 , 17, 2080-2083	3.5	11
237	A summary of recent experimental research on ion energy and charge states of pulsed vacuum arcs 2008 ,		1
236	High charge state ions extracted from metal plasmas in the transition regime from vacuum spark to high current vacuum arc 2008 ,		1
235	Extractable, elevated ion charge states in the transition regime from vacuum sparks to high current vacuum arcs. <i>Applied Physics Letters</i> , 2008 , 92, 041502	3.4	30

234	Studies of III-Nitride Superlattice Structures Implanted with Lanthanide Ions. <i>Materials Research Society Symposia Proceedings</i> , 2008 , 1111, 1		3
233	Measurements of the asymmetric dynamic sheath around a pulse biased sphere immersed in flowing metal plasma. <i>Plasma Sources Science and Technology</i> , 2008 , 17, 035030	3.5	2
232	Some Applications of Cathodic Arc Coatings. <i>Springer Series on Atomic, Optical, and Plasma Physics</i> , 2008 , 429-490	0.4	1
231	Temporal development of ion beam mean charge state in pulsed vacuum arc ion sources. <i>Review of Scientific Instruments</i> , 2008 , 79, 02B301	1.7	8
230	Inverted end-Hall-type low-energy high-current gaseous ion source. <i>Review of Scientific Instruments</i> , 2008 , 79, 02B302	1.7	3
229	A study of vacuum arc ion velocities using a linear set of probes. <i>Journal Physics D: Applied Physics</i> , 2008 , 41, 205210	3	9
228	Observation of Ti ⁴⁺ ions in a high power impulse magnetron sputtering plasma. <i>Applied Physics Letters</i> , 2008 , 93, 071504	3.4	54
227	Effects of ozone oxidation on interfacial and dielectric properties of thin HfO ₂ films. <i>Journal of Applied Physics</i> , 2008 , 104, 054117	2.5	14
226	Functionalization of hydrogen-free diamond-like carbon films using open-air dielectric barrier discharge atmospheric plasma treatments. <i>Applied Surface Science</i> , 2008 , 254, 5323-5328	6.7	16
225	Electrochromically switched, gas-reservoir metal hydride devices with application to energy-efficient windows. <i>Thin Solid Films</i> , 2008 , 517, 1021-1026	2.2	15
224	Physics of plasma-based ion implantation & deposition (PBIID) and high power impulse magnetron sputtering (HIPIMS): A comparison. <i>Physica Status Solidi (A) Applications and Materials Science</i> , 2008 , 205, 965-970	1.6	7
223	Comparative surface and nano-tribological characteristics of nanocomposite diamond-like carbon thin films doped by silver. <i>Applied Surface Science</i> , 2008 , 255, 2551-2556	6.7	158
222	Structure and properties of silver-containing a-C(H) films deposited by plasma immersion ion implantation. <i>Surface and Coatings Technology</i> , 2008 , 202, 3675-3682	4.4	79
221	Coalescence of magnetron-sputtered silver islands affected by transition metal seeding (Ni, Cr, Nb, Zr, Mo, W, Ta) and other parameters. <i>Thin Solid Films</i> , 2008 , 516, 4546-4552	2.2	29
220	MeV-ion beam analysis of the interface between filtered cathodic arc-deposited a-carbon and single crystalline silicon. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2008 , 266, 5175-5179	1.2	1
219	Macroparticles. <i>Springer Series on Atomic, Optical, and Plasma Physics</i> , 2008 , 265-298	0.4	
218	The Interelectrode Plasma. <i>Springer Series on Atomic, Optical, and Plasma Physics</i> , 2008 , 175-225	0.4	1
217	A Brief History of Cathodic Arc Coating. <i>Springer Series on Atomic, Optical, and Plasma Physics</i> , 2008 , 7-74	0.4	0

216	Macroparticle Filters. <i>Springer Series on Atomic, Optical, and Plasma Physics</i> , 2008 , 299-362	0.4	0
215	Cathodic Arc Sources. <i>Springer Series on Atomic, Optical, and Plasma Physics</i> , 2008 , 227-263	0.4	4
214	Cathodic Vacuum Arc Plasma of Thallium. <i>IEEE Transactions on Plasma Science</i> , 2007 , 35, 516-517	1.3	5
213	Plasma biasing to control the growth conditions of diamond-like carbon. <i>Surface and Coatings Technology</i> , 2007 , 201, 4628-4632	4.4	20
212	Physical properties of erbium implanted tungsten oxide films deposited by reactive dual magnetron sputtering. <i>Thin Solid Films</i> , 2007 , 515, 5264-5269	2.2	13
211	Mo-containing tetrahedral amorphous carbon deposited by dual filtered cathodic vacuum arc with selective pulsed bias voltage. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2007 , 259, 867-870	1.2	24
210	Structural and optical evaluation of WOxNy films deposited by reactive magnetron sputtering. <i>Journal of Physics and Chemistry of Solids</i> , 2007 , 68, 2227-2232	3.9	5
209	Metal plasmas for the fabrication of nanostructures. <i>Journal Physics D: Applied Physics</i> , 2007 , 40, 2272-2284		65
208	Neutralized drift compression experiments with a high-intensity ion beam. <i>Nuclear Instruments and Methods in Physics Research, Section A: Accelerators, Spectrometers, Detectors and Associated Equipment</i> , 2007 , 577, 223-230	1.2	8
207	Low-energy linear oxygen plasma source. <i>Review of Scientific Instruments</i> , 2007 , 78, 043304	1.7	9
206	Charge-state-resolved ion energy distribution functions of cathodic vacuum arcs: A study involving the plasma potential and biased plasmas. <i>Journal of Applied Physics</i> , 2007 , 101, 043304	2.5	28
205	Filtered cathodic arc deposition with ion-species-selective bias. <i>Review of Scientific Instruments</i> , 2007 , 78, 063901	1.7	27
204	Puzzling differences in bismuth and lead plasmas: Evidence for the significant role of neutrals in cathodic vacuum arcs. <i>Applied Physics Letters</i> , 2007 , 91, 091502	3.4	19
203	Combined filtered cathodic arc etching pretreatment+magnetron sputter deposition of highly adherent CrN films. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2007 , 25, 543-550	2.9	18
202	High power impulse magnetron sputtering: Current-voltage-time characteristics indicate the onset of sustained self-sputtering. <i>Journal of Applied Physics</i> , 2007 , 102, 113303	2.5	249
201	Production of neutrals and their effects on the ion charge states in cathodic vacuum arc plasmas. <i>Journal of Applied Physics</i> , 2007 , 102, 043303	2.5	40
200	Physics of arcing, and implications to sputter deposition. <i>Thin Solid Films</i> , 2006 , 502, 22-28	2.2	70
199	Measurement of total ion current from vacuum arc plasma sources. <i>Review of Scientific Instruments</i> , 2006 , 77, 03B504	1.7	17

198	Biocompatible Silver-containing a-C:H and a-C coatings: A Comparative Study. <i>Materials Research Society Symposia Proceedings</i> , 2006 , 950, 1		3
197	Influence of argon and oxygen on charge-state-resolved ion energy distributions of filtered aluminum arcs. <i>Journal of Applied Physics</i> , 2006 , 99, 123303	2.5	30
196	Material-dependent high-frequency current fluctuations of cathodic vacuum arcs: Evidence for the ecton cutoff of the fractal model. <i>Journal of Applied Physics</i> , 2006 , 99, 103301	2.5	9
195	Charge state dependence of cathodic vacuum arc ion energy and velocity distributions. <i>Applied Physics Letters</i> , 2006 , 89, 141502	3.4	26
194	Smoothing of ultrathin silver films by transition metal seeding. <i>Solid State Communications</i> , 2006 , 140, 225-229	1.6	58
193	Structural, optical, and electrical properties of WO _x (Ny) films deposited by reactive dual magnetron sputtering. <i>Surface and Coatings Technology</i> , 2006 , 201, 2977-2983	4.4	38
192	Determination of the specific ion erosion of the vacuum arc cathode by measuring the total ion current from the discharge plasma. <i>Technical Physics</i> , 2006 , 51, 1311-1315	0.5	9
191	Time and material dependence of the voltage noise generated by cathodic vacuum arcs. <i>Journal Physics D: Applied Physics</i> , 2005 , 38, 4184-4190	3	19
190	Cathodic arcs: Fractal voltage and cohesive energy rule. <i>Applied Physics Letters</i> , 2005 , 86, 211503	3.4	41
189	. <i>IEEE Transactions on Plasma Science</i> , 2005 , 33, 1532-1536	1.3	62
188	. <i>IEEE Transactions on Plasma Science</i> , 2005 , 33, 1456-1464	1.3	46
187	. <i>IEEE Transactions on Plasma Science</i> , 2005 , 33, 1944-1959	1.3	127
186	Ion charge state fluctuations in vacuum arcs. <i>Journal Physics D: Applied Physics</i> , 2005 , 38, 1021-1028	3	11
185	Neutralized transport experiment. <i>Nuclear Instruments and Methods in Physics Research, Section A: Accelerators, Spectrometers, Detectors and Associated Equipment</i> , 2005 , 544, 225-235	1.2	21
184	Plasma and ion sources in large area coating: A review. <i>Surface and Coatings Technology</i> , 2005 , 200, 1893-1906	4.1	105
183	Instability of a low-pressure hollow-cathode discharge in a magnetic field. <i>Plasma Physics Reports</i> , 2005 , 31, 978-983	1.2	8
182	Charge-state-resolved ion energy distributions of aluminum vacuum arcs in the absence and presence of a magnetic field. <i>Journal of Applied Physics</i> , 2005 , 97, 103306	2.5	33
181	. <i>IEEE Transactions on Plasma Science</i> , 2005 , 33, 205-209	1.3	26

180	Drift compression of an intense neutralized ion beam. <i>Physical Review Letters</i> , 2005 , 95, 234801	7.4	108
179	The kinetic energy of carbon ions in vacuum arc plasmas: A comparison of measuring techniques. <i>Journal of Applied Physics</i> , 2004 , 96, 970-974	2.5	15
178	Results on intense beam focusing and neutralization from the neutralized beam experiment. <i>Physics of Plasmas</i> , 2004 , 11, 2890-2898	2.1	59
177	Observation of self-sputtering in energetic condensation of metal ions. <i>Applied Physics Letters</i> , 2004 , 85, 6137-6139	3.4	28
176	Charge state and time resolved plasma composition of a pulsed zirconium arc in a nitrogen environment. <i>Journal of Applied Physics</i> , 2004 , 96, 4793-4799	2.5	12
175	Effect of ion mass and charge State on transport of vacuum arc plasmas through a biased magnetic filter. <i>IEEE Transactions on Plasma Science</i> , 2004 , 32, 433-439	1.3	8
174	Insights into Bear-frictionless carbon films□ <i>Journal of Applied Physics</i> , 2004 , 95, 7765-7771	2.5	37
173	Fundamentals of pulsed plasmas for materials processing. <i>Surface and Coatings Technology</i> , 2004 , 183, 301-311	4.4	104
172	Some effects of magnetic field on a hollow cathode ion source. <i>Review of Scientific Instruments</i> , 2004 , 75, 1030-1033	1.7	12
171	Design and characterization of a neutralized-transport experiment for heavy-ion fusion. <i>Physical Review Special Topics: Accelerators and Beams</i> , 2004 , 7,		31
170	Asymmetric injection of cathodic arc plasma into a macroparticle filter. <i>Journal of Applied Physics</i> , 2004 , 95, 7602-7606	2.5	4
169	Tracking down the origin of arc plasma science I. Early pulsed and oscillating discharges. <i>IEEE Transactions on Plasma Science</i> , 2003 , 31, 1052-1059	1.3	16
168	Tracking down the origin of arc plasma Science-II. Early continuous discharges. <i>IEEE Transactions on Plasma Science</i> , 2003 , 31, 1060-1069	1.3	22
167	Bias and self-bias of magnetic macroparticle filters for cathodic arc plasmas. <i>Journal of Applied Physics</i> , 2003 , 93, 8890-8897	2.5	17
166	Flexible system for multiple plasma immersion ion implantation-deposition processes. <i>Review of Scientific Instruments</i> , 2003 , 74, 5137-5140	1.7	9
165	Temporal development of the composition of Zr and Cr cathodic arc plasma streams in a N2 environment. <i>Journal of Applied Physics</i> , 2003 , 94, 1414-1419	2.5	19
164	Time-resolved emittance of a bismuth ion beam from a pulsed vacuum arc ion source. <i>Journal of Applied Physics</i> , 2003 , 93, 2298-2300	2.5	9
163	Coalescence of nanometer silver islands on oxides grown by filtered cathodic arc deposition. <i>Applied Physics Letters</i> , 2003 , 82, 1634-1636	3.4	46

162	Ion energy distribution functions of vacuum arc plasmas. <i>Journal of Applied Physics</i> , 2003 , 93, 1899-1906	2.5	73
161	Energetic deposition using filtered cathodic arc plasmas. <i>Vacuum</i> , 2002 , 67, 673-686	3.7	82
160	From plasma immersion ion implantation to deposition: a historical perspective on principles and trends. <i>Surface and Coatings Technology</i> , 2002 , 156, 3-12	4.4	69
159	Imaging the separation of cathodic arc plasma and macroparticles in curved magnetic filters. <i>IEEE Transactions on Plasma Science</i> , 2002 , 30, 108-109	1.3	12
158	Plasma chemistry fluctuations in a reactive arc plasma in the presence of magnetic fields. <i>Applied Physics Letters</i> , 2002 , 80, 4109-4111	3.4	9
157	Atomic scale heating in cathodic arc plasma deposition. <i>Applied Physics Letters</i> , 2002 , 80, 1100-1102	3.4	86
156	Angularly resolved measurements of ion energy of vacuum arc plasmas. <i>Applied Physics Letters</i> , 2002 , 80, 2457-2459	3.4	35
155	Magnetic field effect on the sheath thickness in plasma immersion ion implantation. <i>Applied Physics Letters</i> , 2002 , 81, 1183-1185	3.4	43
154	Developing high brightness beams for heavy ion driven inertial fusion. <i>Review of Scientific Instruments</i> , 2002 , 73, 1084-1086	1.7	2
153	Reducing ion-beam noise of vacuum arc ion sources. <i>Review of Scientific Instruments</i> , 2002 , 73, 732-734	1.7	9
152	Further development of low noise vacuum arc ion source. <i>Review of Scientific Instruments</i> , 2002 , 73, 735-737	1.7	12
151	Inductive energy storage driven vacuum arc thruster. <i>Review of Scientific Instruments</i> , 2002 , 73, 925-927	1.7	53
150	Two-dimensional sample temperature modeling in separation by plasma implantation of oxygen (SPIMOX) process. <i>IEEE Transactions on Plasma Science</i> , 2002 , 30, 423-427	1.3	1
149	Ion flux from vacuum arc cathode spots in the absence and presence of a magnetic field. <i>Journal of Applied Physics</i> , 2002 , 91, 4824-4832	2.5	295
148	Emission Methods of Experimental Investigations of Ion Velocities in Vacuum Arc Plasmas 2002 , 105-113		
147	Cohesive Energy Rule for Vacuum Arcs 2002 , 1-14		7
146	Guest editorial special issue on vacuum discharge plasmas. <i>IEEE Transactions on Plasma Science</i> , 2001 , 29, 654-656	1.3	
145	Regulation of the alpha-secretase ADAM10 by its prodomain and proprotein convertases. <i>FASEB Journal</i> , 2001 , 15, 1837-9	0.9	188

144	Arc-discharge ion sources for heavy ion fusion. <i>Nuclear Instruments and Methods in Physics Research, Section A: Accelerators, Spectrometers, Detectors and Associated Equipment</i> , 2001 , 464, 569-575	1.2	15
143	Recent advances in high current vacuum arc ion sources for heavy ion fusion. <i>Nuclear Instruments and Methods in Physics Research, Section A: Accelerators, Spectrometers, Detectors and Associated Equipment</i> , 2001 , 464, 576-581	1.2	4
142	Width, structure and stability of sheaths in metal plasma immersion ion implantation and deposition: measurements and analytical considerations. <i>Surface and Coatings Technology</i> , 2001 , 136, 85-92	4.4	45
141	Measurements of secondary electrons emitted from conductive substrates under high-current metal ion bombardment. <i>Surface and Coatings Technology</i> , 2001 , 136, 111-116	4.4	15
140	Generation of Multiply Charged Ions in the Plasma of a Vacuum Arc Discharge. <i>Russian Physics Journal</i> , 2001 , 44, 912-920	0.7	5
139	MBE growth of (In)GaAsN on GaAs using a constricted DC plasma source. <i>Semiconductor Science and Technology</i> , 2001 , 16, 413-419	1.8	4
138	Energetics of vacuum arc cathode spots. <i>Applied Physics Letters</i> , 2001 , 78, 2837-2839	3.4	18
137	Magnetic system for producing uniform coatings using a filtered cathodic arc. <i>Plasma Sources Science and Technology</i> , 2001 , 10, 606-613	3.5	15
136	Magnetic-field-dependent plasma composition of a pulsed aluminum arc in an oxygen ambient. <i>Applied Physics Letters</i> , 2001 , 78, 150-152	3.4	26
135	Synthesis of Ultrathin Ta-C Films by Twist-Filtered Cathodic Arc Carbon Plasmas. <i>Materials Research Society Symposia Proceedings</i> , 2001 , 675, 1		7
134	Compact vacuum arc micro-thruster for small satellite systems 2001 ,		4
133	Ultrathin diamond-like carbon films deposited by filtered carbon vacuum arcs. <i>IEEE Transactions on Plasma Science</i> , 2001 , 29, 768-775	1.3	49
132	A periodic table of ion charge-state distributions observed in the transition region between vacuum sparks and vacuum arcs. <i>IEEE Transactions on Plasma Science</i> , 2001 , 29, 393-398	1.3	42
131	Correlation between cathode properties, burning voltage, and plasma parameters of vacuum arcs. <i>Journal of Applied Physics</i> , 2001 , 89, 7764-7771	2.5	75
130	Review of cathodic arc deposition technology at the start of the new millennium. <i>Surface and Coatings Technology</i> , 2000 , 133-134, 78-90	4.4	169
129	Twist filter for the removal of macroparticles from cathodic arc plasmas. <i>Surface and Coatings Technology</i> , 2000 , 133-134, 96-100	4.4	35
128	Chopping effect observed at cathodic arc initiation. <i>IEEE Transactions on Plasma Science</i> , 2000 , 28, 1303-1304	1.3	13
127	Effect of multiple current spikes on the enhancement of ion charge states of vacuum arc plasmas. <i>Journal of Applied Physics</i> , 2000 , 87, 8345-8350	2.5	31

126	Breakdown of the high-voltage sheath in metal plasma immersion ion implantation. <i>Applied Physics Letters</i> , 2000 , 76, 28-30	3.4	22
125	Enhanced ion charge states in vacuum arc plasmas using a current spike method. <i>Review of Scientific Instruments</i> , 2000 , 71, 701-703	1.7	37
124	Pulsed vacuum-arc ion source operated with a triggerless arc initiation method. <i>Review of Scientific Instruments</i> , 2000 , 71, 827-829	1.7	46
123	Magnetic-field-dependent plasma composition of a pulsed arc in a high-vacuum ambient. <i>Applied Physics Letters</i> , 2000 , 76, 1531-1533	3.4	18
122	Ion velocities in vacuum arc plasmas. <i>Journal of Applied Physics</i> , 2000 , 88, 5618-5622	2.5	187
121	Temporal development of the plasma composition of a pulsed aluminum plasma stream in the presence of oxygen. <i>Applied Physics Letters</i> , 1999 , 75, 612-614	3.4	32
120	Efficient, compact power supply for repetitively pulsed, triggerless cathodic arcs. <i>Review of Scientific Instruments</i> , 1999 , 70, 4532-4535	1.7	24
119	Recent advances in surface processing with metal plasma and ion beams. <i>Surface and Coatings Technology</i> , 1999 , 112, 271-277	4.4	51
118	Approaches to rid cathodic arc plasmas of macro- and nanoparticles: a review. <i>Surface and Coatings Technology</i> , 1999 , 120-121, 319-330	4.4	177
117	Vacuum-arc-generated macroparticles in the nanometer range. <i>IEEE Transactions on Plasma Science</i> , 1999 , 27, 1030-1033	1.3	18
116	Velocity distribution of carbon macroparticles generated by pulsed vacuum arcs. <i>Plasma Sources Science and Technology</i> , 1999 , 8, 567-571	3.5	24
115	Ion charge state distributions of alloy-cathode vacuum arc plasmas. <i>IEEE Transactions on Plasma Science</i> , 1999 , 27, 911-914	1.3	16
114	Paragenetic suppressors of suppressor genes--a new class of oncodeterminants. <i>Journal of Cancer Research and Clinical Oncology</i> , 1999 , 125, 123-33	4.9	10
113	Evaluation of the plasma distribution of a quasi-linear constricted plasma source. <i>IEEE Transactions on Plasma Science</i> , 1999 , 27, 82-83	1.3	5
112	Free-boundary vacuum arc plasma jet expansion in a curved magnetic field. <i>IEEE Transactions on Plasma Science</i> , 1999 , 27, 613-619	1.3	11
111	Plasma fluctuations, local partial Saha equilibrium, and the broadening of vacuum-arc ion charge state distributions. <i>IEEE Transactions on Plasma Science</i> , 1999 , 27, 1060-1067	1.3	28
110	Characterization of a linear venetian-blind macroparticle filter for cathodic vacuum arcs. <i>IEEE Transactions on Plasma Science</i> , 1999 , 27, 1197-1202	1.3	17
109	Low-energy ion assisted deposition of epitaxial gallium nitride films. <i>Nuclear Instruments & Methods in Physics Research B</i> , 1999 , 148, 406-410	1.2	6

108	Designing advanced filters for macroparticle removal from cathodic arc plasmas. <i>Plasma Sources Science and Technology</i> , 1999 , 8, 488-493	3.5	28
107	Ion implantation post-processing of amorphous carbon films. <i>Diamond and Related Materials</i> , 1999 , 8, 451-456	3.5	9
106	Hydrogen uptake in alumina thin films synthesized from an aluminum plasma stream in an oxygen ambient. <i>Applied Physics Letters</i> , 1999 , 74, 200-202	3.4	70
105	Study of Low-Energy Ion Assisted Epitaxy of GaN Films: Influence of the Initial Growth Rate. <i>Materials Research Society Symposia Proceedings</i> , 1999 , 585, 239		5
104	Ion charge state distributions of pulsed vacuum arcs-interpretation of their temporal development. <i>IEEE Transactions on Plasma Science</i> , 1998 , 26, 118-119	1.3	11
103	Effect of the pulse repetition rate on the composition and ion charge-state distribution of pulsed vacuum arcs. <i>IEEE Transactions on Plasma Science</i> , 1998 , 26, 220-226	1.3	43
102	Surface resistivity tailoring of ceramics by metal ion implantation. <i>Surface and Coatings Technology</i> , 1998 , 103-104, 46-51	4.4	15
101	A filamentless ion source for materials processing. <i>Review of Scientific Instruments</i> , 1998 , 69, 880-882	1.7	2
100	Characterization of a low-energy constricted-plasma source. <i>Review of Scientific Instruments</i> , 1998 , 69, 1340-1343	1.7	36
99	'Triggerless' triggering of vacuum arcs. <i>Journal Physics D: Applied Physics</i> , 1998 , 31, 584-587	3	94
98	Streaming metal plasma generation by vacuum arc plasma guns. <i>Review of Scientific Instruments</i> , 1998 , 69, 801-803	1.7	73
97	Ion charge state distributions of pulsed vacuum arc plasmas in strong magnetic fields. <i>Review of Scientific Instruments</i> , 1998 , 69, 1332-1335	1.7	43
96	Results from energetic electron beam metal vapor vacuum arc and Z-discharge plasma metal vapor vacuum arc: Development of new sources of intense high charge state heavy-ion beams. <i>Review of Scientific Instruments</i> , 1998 , 69, 798-800	1.7	15
95	Interaction of vacuum-arc-generated macroparticles with a liquid surface. <i>Applied Physics Letters</i> , 1998 , 73, 3199-3201	3.4	8
94	Growth and decay of macroparticles: A feasible approach to clean vacuum arc plasmas?. <i>Journal of Applied Physics</i> , 1997 , 82, 3679-3688	2.5	35
93	Ion charge state distributions of vacuum arc plasmas: The origin of species. <i>Physical Review E</i> , 1997 , 55, 969-981	2.4	251
92	S-shaped magnetic macroparticle filter for cathodic arc deposition. <i>IEEE Transactions on Plasma Science</i> , 1997 , 25, 670-674	1.3	59
91	Vacuum-spark metal ion source based on a modified Marx generator. <i>IEEE Transactions on Plasma Science</i> , 1997 , 25, 718-721	1.3	11

90	The effect of additional ion/plasma assistance in CNx-film deposition based on a filtered cathodic arc. <i>Thin Solid Films</i> , 1997 , 311, 151-156	2.2	5
89	High energy implantation with high-charge-state ions in a vacuum arc ion implanter. <i>Nuclear Instruments & Methods in Physics Research B</i> , 1997 , 127-128, 779-781	1.2	8
88	High energy metal ion implantation using a novel, broad-beam, Marx-generator-based ion source <i>Nuclear Instruments & Methods in Physics Research B</i> , 1997 , 127-128, 992-995	1.2	4
87	Macroparticle filtering of high-current vacuum arc plasmas. <i>IEEE Transactions on Plasma Science</i> , 1997 , 25, 660-664	1.3	47
86	Metal plasma immersion ion implantation and deposition: a review. <i>Surface and Coatings Technology</i> , 1997 , 93, 158-167	4.4	213
85	Optics of Human Skin: UV Effects Investigated with Dye Lasers 1997 , 205-210		
84	Diamond growth on hard carbon films. <i>Diamond and Related Materials</i> , 1996 , 5, 1080-1086	3.5	5
83	Hardness, elastic modulus, and structure of very hard carbon films produced by cathodic-arc deposition with substrate pulse biasing. <i>Applied Physics Letters</i> , 1996 , 68, 779-781	3.4	231
82	Hollow-anode plasma source for molecular beam epitaxy of gallium nitride. <i>Review of Scientific Instruments</i> , 1996 , 67, 905-907	1.7	31
81	Properties of cathodic arc deposited high-temperature superconducting composite thin films on Ag substrates. <i>Physica C: Superconductivity and Its Applications</i> , 1996 , 270, 173-179	1.3	5
80	High-resolution imaging of vacuum arc cathode spots. <i>IEEE Transactions on Plasma Science</i> , 1996 , 24, 69-70	1.3	14
79	Ion charge state distributions in high current vacuum arc plasmas in a magnetic field. <i>IEEE Transactions on Plasma Science</i> , 1996 , 24, 1174-1183	1.3	137
78	Plasma and Ion Beam Tools for Enhanced Battery Electrode Performance. <i>Materials Research Society Symposia Proceedings</i> , 1996 , 438, 543		
77	Pressure-Controlled GaN MBE Growth Using a Hollow Anode Nitrogen Ion Source. <i>Materials Research Society Symposia Proceedings</i> , 1996 , 449, 221		9
76	Cathodic arc deposition of copper oxide thin films. <i>Surface and Coatings Technology</i> , 1996 , 78, 168-172	4.4	17
75	Surface modification of nickel battery electrodes by cobalt plasma immersion ion implantation and deposition. <i>Surface and Coatings Technology</i> , 1996 , 85, 75-79	4.4	15
74	Recent advances in vacuum arc ion sources. <i>Surface and Coatings Technology</i> , 1996 , 84, 550-556	4.4	42
73	Peristaltic ion source (invited). <i>Review of Scientific Instruments</i> , 1996 , 67, 956-958	1.7	

72	Effect of pretreatment process parameters on diamond nucleation on unscratched silicon substrates coated with amorphous carbon films. <i>Journal of Applied Physics</i> , 1996 , 79, 485-492	2.5	16
71	High ion charge states in a high-current, short-pulse, vacuum arc ion source. <i>Review of Scientific Instruments</i> , 1996 , 67, 1202-1204	1.7	26
70	In-situ deposition of sacrificial layers during ion implantation: concept and simulation 1996 , 1089-1092		
69	Synthesis of unattainable ion implantation profiles [pseudo-implantation] 1996 , 646-650		
68	Formation of metal oxides by cathodic arc deposition. <i>Surface and Coatings Technology</i> , 1995 , 76-77, 167-173	4.4	41
67	Synthesis of unattainable ion implantation profiles [pseudo-implantation] <i>Nuclear Instruments & Methods in Physics Research B</i> , 1995 , 106, 646-650	1.2	10
66	Increasing the retained dose by plasma immersion ion implantation and deposition. <i>Nuclear Instruments & Methods in Physics Research B</i> , 1995 , 102, 132-135	1.2	21
65	. <i>IEEE Transactions on Applied Superconductivity</i> , 1995 , 5, 2011-2014	1.8	4
64	Nanoindentation and Nanoscratching of Hard Carbon Coatings for Magnetic Disks. <i>Materials Research Society Symposia Proceedings</i> , 1995 , 383, 447		304
63	The working principle of the hollow-anode plasma source. <i>Plasma Sources Science and Technology</i> , 1995 , 4, 571-575	3.5	63
62	Effect of intrinsic growth stress on the Raman spectra of vacuum-arc-deposited amorphous carbon films. <i>Applied Physics Letters</i> , 1995 , 66, 3444-3446	3.4	93
61	Transport of vacuum arc plasmas through magnetic macroparticle filters. <i>Plasma Sources Science and Technology</i> , 1995 , 4, 1-12	3.5	152
60	Development of hard carbon coatings for thin-film tape heads. <i>IEEE Transactions on Magnetics</i> , 1995 , 31, 2976-2978	2	15
59	. <i>IEEE Transactions on Plasma Science</i> , 1995 , 23, 275-282	1.3	44
58	Mechanical Properties of Amorphous Hard Carbon Films Prepared by Cathodic ARC Deposition. <i>Materials Research Society Symposia Proceedings</i> , 1995 , 383, 453		16
57	Film Synthesis on Powders by Cathodic ARC Plasma Deposition. <i>Materials Research Society Symposia Proceedings</i> , 1995 , 388, 215		4
56	New Developments in Metal Ion Implantation by Vacuum Arc Ion Sources and Metal Plasma Immersion. <i>Materials Research Society Symposia Proceedings</i> , 1995 , 396, 467		2
55	Surface modification of magnetic recording heads by plasma immersion ion implantation and deposition. <i>Journal of Applied Physics</i> , 1994 , 76, 1656-1664	2.5	19

54	Metal ion implantation: Conventional versus immersion. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1994 , 12, 823		34
53	Effect of vacuum arc deposition parameters on the properties of amorphous carbon thin films. <i>Surface and Coatings Technology</i> , 1994 , 68-69, 388-393	4.4	121
52	Vacuum arc ion sources: Some vacuum arc basics and recent results (invited). <i>Review of Scientific Instruments</i> , 1994 , 65, 1253-1258	1.7	21
51	Effect of duct bias on transport of vacuum arc plasmas through curved magnetic filters. <i>Journal of Applied Physics</i> , 1994 , 75, 4900-4905	2.5	87
50	Vacuum-arc plasma deposition: macroparticle filtering, scaling, and other problems 1994 ,		1
49	Electron emission from pseudospark cathodes. <i>Journal of Applied Physics</i> , 1994 , 76, 1494-1502	2.5	33
48	Vacuum arc ion source with filtered plasma for macroparticle-free implantation. <i>Review of Scientific Instruments</i> , 1994 , 65, 1319-1321	1.7	13
47	Focused injection of vacuum arc plasmas into curved magnetic filters. <i>Journal of Applied Physics</i> , 1994 , 75, 4895-4899	2.5	46
46	Metal plasma immersion ion implantation and deposition using vacuum arc plasma sources. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1994 , 12, 815		140
45	. <i>IEEE Transactions on Plasma Science</i> , 1993 , 21, 440-446	1.3	93
44	. <i>IEEE Transactions on Plasma Science</i> , 1993 , 21, 305-311	1.3	52
43	Macroparticle-free thin films produced by an efficient vacuum arc deposition technique. <i>Journal of Applied Physics</i> , 1993 , 74, 4239-4241	2.5	97
42	Low Energy Ion Implantation / Deposition as a Film Synthesis and Bonding Tool. <i>Materials Research Society Symposia Proceedings</i> , 1993 , 316, 833		10
41	Model for explosive electron emission in a pseudospark "superdense glow". <i>Physical Review Letters</i> , 1993 , 71, 364-367	7.4	37
40	Joining of Metal Films to Carbon-Carbon Composite Material by Metal Plasma Immersion Ion Implantation. <i>Materials Research Society Symposia Proceedings</i> , 1993 , 314, 205		5
39	Vacuum arc deposition of multilayer X-ray mirrors. <i>Surface and Coatings Technology</i> , 1993 , 61, 257-261	4.4	8
38	Plasma synthesis of metallic and composite thin films with atomically mixed substrate bonding. <i>Nuclear Instruments & Methods in Physics Research B</i> , 1993 , 80-81, 1281-1287	1.2	77
37	Vacuum arc cathode spot parameters from high-resolution luminosity measurements. <i>Journal of Applied Physics</i> , 1992 , 71, 4763-4770	2.5	26

36	Pressure ionization: its role in metal vapour vacuum arc plasmas and ion sources. <i>Plasma Sources Science and Technology</i> , 1992 , 1, 263-270	3.5	34
35	Brightness distribution and current density of vacuum arc cathode spots. <i>Journal Physics D: Applied Physics</i> , 1992 , 25, 1591-1599	3	38
34	. <i>IEEE Transactions on Plasma Science</i> , 1992 , 20, 466-472	1.3	124
33	Electrode behaviour of pulsed high-pressure sodium lamps. <i>Lighting Research & Technology</i> , 1991 , 23, 81-84		1
32	. <i>IEEE Transactions on Plasma Science</i> , 1991 , 19, 324-328	1.3	3
31	. <i>IEEE Transactions on Plasma Science</i> , 1991 , 19, 20-24	1.3	58
30	Emission spectroscopy of low-current vacuum arcs. <i>Journal Physics D: Applied Physics</i> , 1991 , 24, 1986-1992		42
29	Cathode mode transition in high-pressure discharge lamps at start-up. <i>Lighting Research & Technology</i> , 1990 , 22, 111-115		14
28	Effects of Non-Ideality and Non-Equilibrium in the Cathode Spot Plasma of Vacuum Arcs. <i>Contributions To Plasma Physics</i> , 1989 , 29, 537-543	1.4	22
27	. <i>IEEE Transactions on Plasma Science</i> , 1989 , 17, 653-656	1.3	15
26	Study of an Underexpanded Plasma Jet II. Diagnostics with Microwaves. <i>Contributions To Plasma Physics</i> , 1988 , 28, 537-542	1.4	3
25	Frozen state of ionisation in a cathodic plasma jet of a vacuum arc. <i>Journal Physics D: Applied Physics</i> , 1988 , 21, 213-215	3	45
24	Study of an Underexpanded Plasma Jet. <i>Beitrage Aus Der Plasmaphysik</i> , 1987 , 27, 203-221		1
23	Recombination of a Xenon Plasma Jet. <i>Beitrage Aus Der Plasmaphysik</i> , 1987 , 27, 373-398		
22	A high-voltage surface effect on dielectrics in vacuum. <i>Journal Physics D: Applied Physics</i> , 1986 , 19, L75-L77		1
21	Lichtenberg Figures on Dielectrics in Gases and in Vacuum. <i>Beitrage Aus Der Plasmaphysik</i> , 1985 , 25, 315-328		5
20	Xiphophorus as an in vivo model for studies on normal and defective control of oncogenes. <i>Advances in Cancer Research</i> , 1984 , 42, 191-275	5.9	86
19	Investigations on the mechanism of photodynamic action of different psoralens with DNA. <i>Biophysics of Structure and Mechanism</i> , 1983 , 10, 11-30		12

18	365. Klinische und experimentelle Untersuchungen an Kava-Kathetern. <i>Langenbecks Archiv Fur Chirurgie</i> , 1983 , 361, 911-911		
17	Microcalorimetric investigations of the metabolism of isolated human epidermis. <i>Archives of Dermatological Research</i> , 1979 , 265, 173-80	3-3	5
16	Models of DNA-dye-complexes: Energy transfer and molecular structures as evaluated by laser excitation. <i>Applied Physics Berlin</i> , 1979 , 18, 333-338		20
15	Genetics of susceptibility in the platyfish/swordtail tumor system to develop fibrosarcoma and rhabdomyosarcoma following treatment with N-methyl-N-nitrosourea (MNU). <i>Zeitschrift Für Krebsforschung Und Klinische Onkologie</i> , 1978 , 91, 301-15		20
14	Genetic basis of susceptibility for development of neoplasms following treatment with N-methyl-N-nitrosourea (MNU) or x-rays in the platyfish/swordtail system. <i>Experientia</i> , 1978 , 34, 780-2		47
13	Etiology of cancer as studied in the platyfish-swordtail system. <i>Biochimica Et Biophysica Acta: Reviews on Cancer</i> , 1978 , 516, 61-95	11.2	29
12	Orthotopic and heterotopic autotransplantation of the rat kidney. <i>Research in Experimental Medicine</i> , 1978 , 172, 123-9		
11	Energy transfer in nucleic acid-dye complexes. <i>Optics Communications</i> , 1978 , 26, 339-342	2	16
10	X-ray induced mutations of the genetically-determined melanoma system of Xiphophorin fish. <i>Experientia</i> , 1971 , 27, 931-2		14
9	Effects of x-irradiation on the genetically-determined melanoma system of xiphophorin fish. <i>Experientia</i> , 1971 , 27, 695-7		16
8	XY females caused by x-irradiation. <i>Experientia</i> , 1969 , 25, 871		3
7	Vacuum-arc-generated macro particles in the nanometer range		1
6	Measurement of total ion flux in vacuum arc discharges		3
5	Influence of a strong pulsed magnetic field on the charge state distribution of ions in a vacuum arc plasma		3
4			2
3	Focusing and neutralization of intense beams		3
2	Neutralized transport of high intensity beams		2
1	Influence of the magnetic field on the discharge physics of a high power impulse magnetron sputtering discharge. <i>Journal Physics D: Applied Physics</i> ,	3	6

